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Electron or Ion Sources and Systems

N. Economou, L. Harriott, P. Kruit, A.D. Brodie, J. Maldonado

EUV Lithography

M. Feldman, K. Goldberg, P. Naulleau, U. Behringer

Optical Lithography

S. Brueck, T. Brunner, M. Rothschild, S. Okazaki, T. Groves, B. Smith, S.R. Palmer,

Maskless Lithography

D. Joy, J. Maldonado, R. Menon, D. Pickard, C. Bevis, M. Shattenburg, M. Rothschild, S. Brueck

Computation Lithography, Modeling, Simulation and CAD

R. Engelstad, M. Peckerar, F. Schellenberg, K. Turner, D. Melville, C. Mack, T. Brunner, L. Melvin

Nano-Imprint, Soft Lithograph

S. Chou, D. Kercher, M. Qi, D. Resnick, G. Wilson, D. Olynick, S. Matsui

Resists

R. Brainard, T. Fedynyshyn, C. Soles, G. Wallraff, F. Houle, K. Berggren

Metrology, Imaging and Alignment

E. Anderson, E. Moon, P. Russell L. Baghaei Rad, D. Joy, R. Heilmann

Atomic, Molecular Scale, and Tip Based Processing

J. Randall, C. Hanson, G. Zeltzer, B. King

Nanofabrication: Directed Self Assembly

J. Cheng, P. Nealey, H. Yoshida, R. Ruiz, M. Peckerar, L. Dobisz, T. Fedynyshyn, K. Berggren

Nanofabrication, Nanostructures & Pattern Transfer

E. Gogolides, R. Heilmann, M. Qi, M. Raghunath, M. Horn, J. Wendt, D. Olynick, D. Manchini

Nanomaterials: Graphene, Nanotubes, Metamaterials and Flexible Electronics

R. Murali, Q. Xia, G. Malliaras

Nanophotonics, Plasmonics & Applications

A. Liddle, R. Menon, D. Pickard, S. Brueck, M. Horn

Nano-Biology Applications

S. Wind, R. Luttge, R. Farrow, F. Ligler, C. Wilkison, J. Grote

Nano-Electronics Applications

J. Cleaver, K. Berggren, A. Dzurak, Q. Xia

Emerging Technologies

C. Black, D. Herr, D. Tanenbaum, M. Fritze, S. Matsui, C. Hanson, D.P. Kern, R. F. Pease, H. Smith, G. Willson

Ultrahigh Density Data Storage

C. Ross, K. Lee, S. Assefa, C. Marrian, E. Dobisz, S. Xiao

Nano-MEMS

L. Ocola, J. Greer, R. Cheung, U. Behringer

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